

Notice of References Cited

Application/Control No.

10/075,602

Applicant(s)/Patent Under
Reexamination
HUNG ET AL.

Examiner

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Art Unit

1765

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*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
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	B	US-4214946	07-1980	Forget et al.	438/712
	C	US-4713141	12-1987	Tsang	438/714
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	E	US-5202291	04-1993	Charvat et al.	438/696
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NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Abraham et al., Methods and Apparatus for Etching Semiconductor Wafers, August 21, 1997, PCT WO 97/30472, pp. 1-23.
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*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
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